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14. The substrate processing system of claim 13 wherein said impedance tuner is coupled between said substrate holder and a low frequency RF generator.

REMARKS

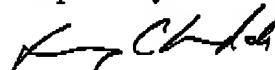
Claims 3-6, 11-14, 16, 19, 20, 23, 24, and 26-30 are pending.

Claim 21 has been canceled because the features of claim 21 are recited in claim 11 from which claim 21 depends.

Claims 3, 13, and 14 have been amended to correct minor informalities. More specifically, the term "pedestal" which has no antecedence basis, has been changed to --substrate holder-- in claims 13 and 14. Claim 3 has been amended because the processor is recited in claim 11 from which claim 3 depends.

No new matter has been introduced, and no new issue has been raised. Applicants believe the claims comply with 35 U.S.C. § 112. Entry of the amendment is respectfully requested.

Respectfully submitted,



Chun-Pok Leung  
Reg. No. 41,405

TOWNSEND and TOWNSEND and CREW LLP  
Tel: (415) 576-0200  
Fax: (415) 576-0300  
RL  
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VERSION WITH MARKINGS TO SHOW CHANGES MADE

IN THE CLAIMS:

Please cancel claim 21 and amend claims 13 and 14 as follows.

3. The substrate processing system of claim 11 [further comprising a computer processor communicatively coupled to said impedance monitor so that] wherein said [computer] processor receives as an input the measured impedance level of said plasma.

13. The substrate processing system of claim 11 further comprising an impedance tuner coupled in series to said [pedestal] substrate holder.

14. The substrate processing system of claim 13 wherein said impedance tuner is coupled between said [pedestal] substrate holder and a low frequency RF generator.

21. CANCELED.

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